

SCANNING ELECTRON MICROSCOPE (SEM)

MANUFACTURER : FEI Company

MODEL : Quanta 3D FEG

Samples

- Equipped with a Field Effect Gun (FEG) allowing the observation of non-conducting samples
- Equipped with a Ga⁺ ion gun: 2 to 30 kV, 1 pA to 65 nA with a resolution of 7 nm

Analysis

- Electron gun: 200 V to 30 kV, 200 nA maximum
- Resolution : 1,2 nm

Variants

- Energy Dispersive Spectrometer (EDS) for X-ray elemental analysis

Applications

- Nanometric-scale sample observation (SEM)
- X-ray elemental analysis (EDS)
- Nanometric-scale etch (FIB)
- Cross-section analysis of multilayer films (FIB-SEM)